



**KETEK GmbH Munich - Germany**

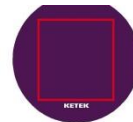
# **Silicon Photomultipliers with enhanced Blue-Light Sensitivity**

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**KETEK**

**Creative Detector Solutions**



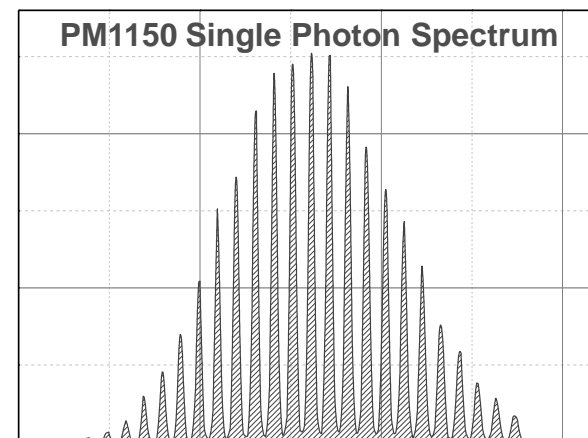
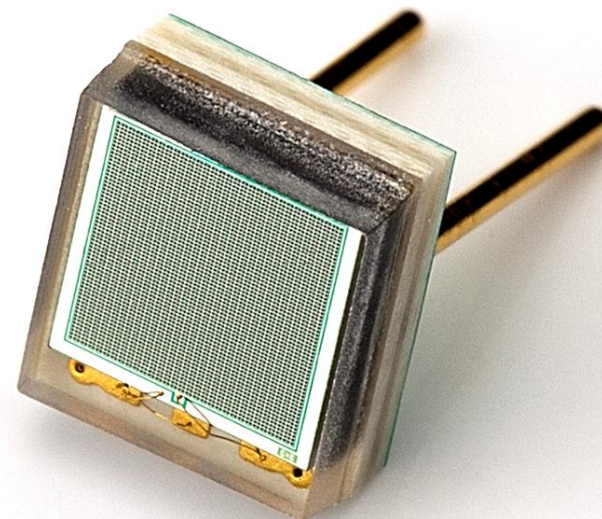
**Creative Detector Solutions**

**PhotoDet 2012, June 13-15, 2012, LAL Orsay, France**

- KETEK SiPM technology
- PDE of different microcell types
- Dark rate
- Optical cross talk
- Temperature coefficient of the gain

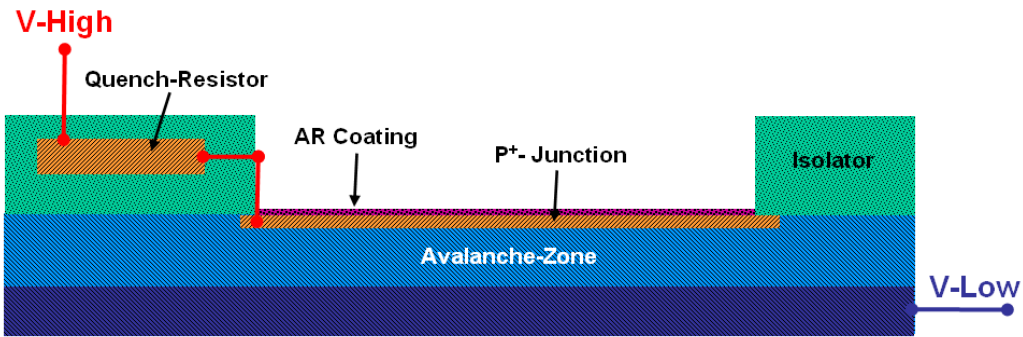
## PM3350

3 x 3mm<sup>2</sup> active area; 50 μm microcell type; peak wavelength 420 nm; plastic package



# Basic Construction of the KETEK Microcell

## Section of KETEK Basic Microcell



- Silicon **P on N** structure with high Geiger efficiency
- **Shallow entrance window** with high quantum efficiency
- Optimized **geometrical fill factor**
- ⇒ **High photon detection efficiency**

- Available in two technologies -

## Non-Trench Technology

- Technology optimized for **maximum GE**
- Devices with very **high PDE**
- Particularly suitable for small microcells and small active area

## Trench Technology

- **Reduced direct cross talk** due to optical isolation trench between single microcells
- **Improved device scalability** due to reduced parasitic RC-values
- Particularly suitable for large microcells and large area devices

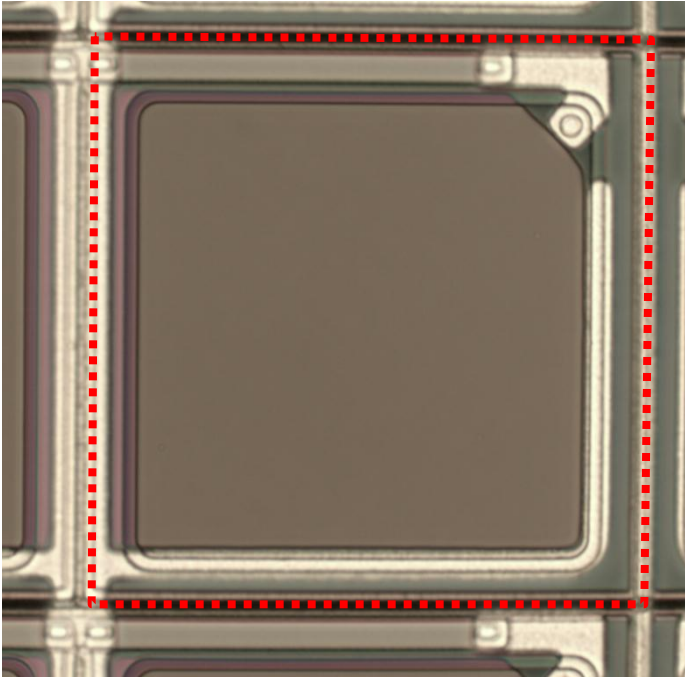


# KETEK Trench Technology

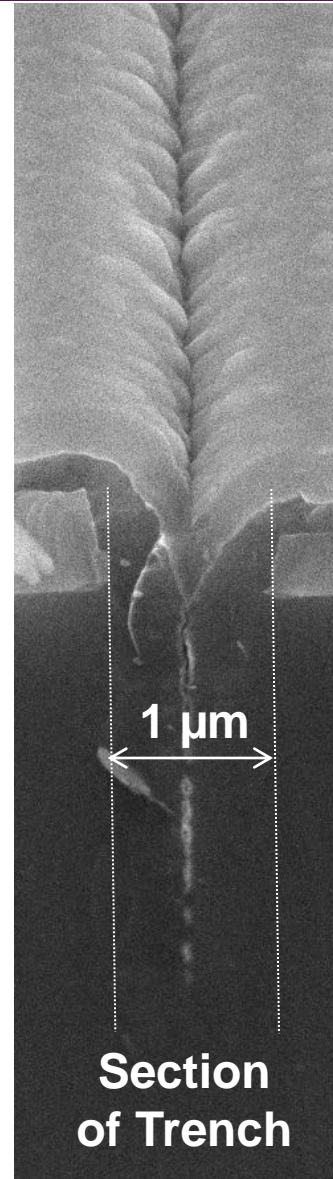
## Section

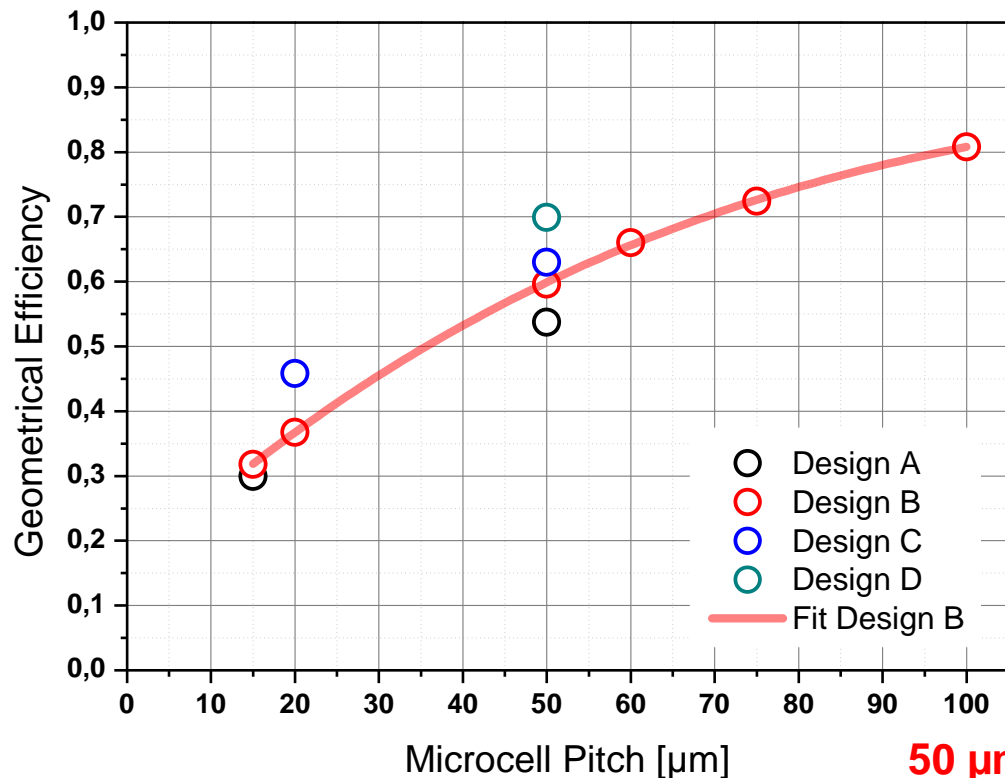


## Top View

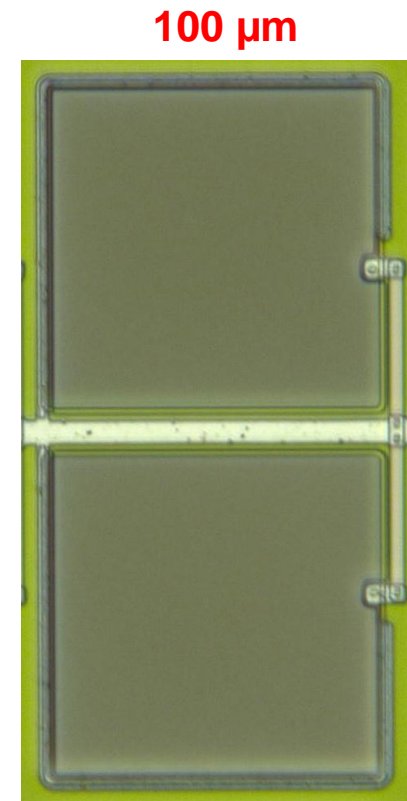
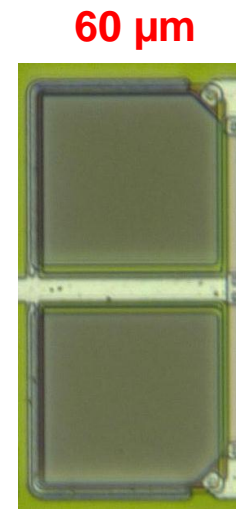
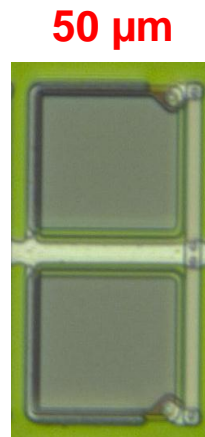
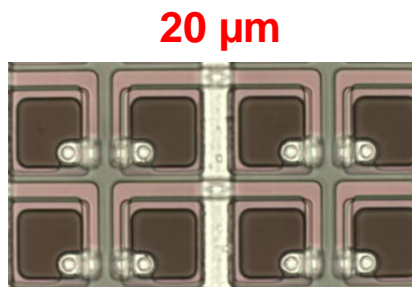
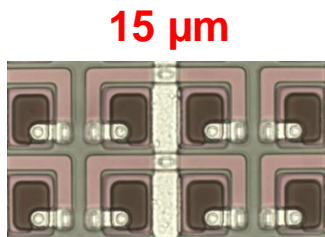


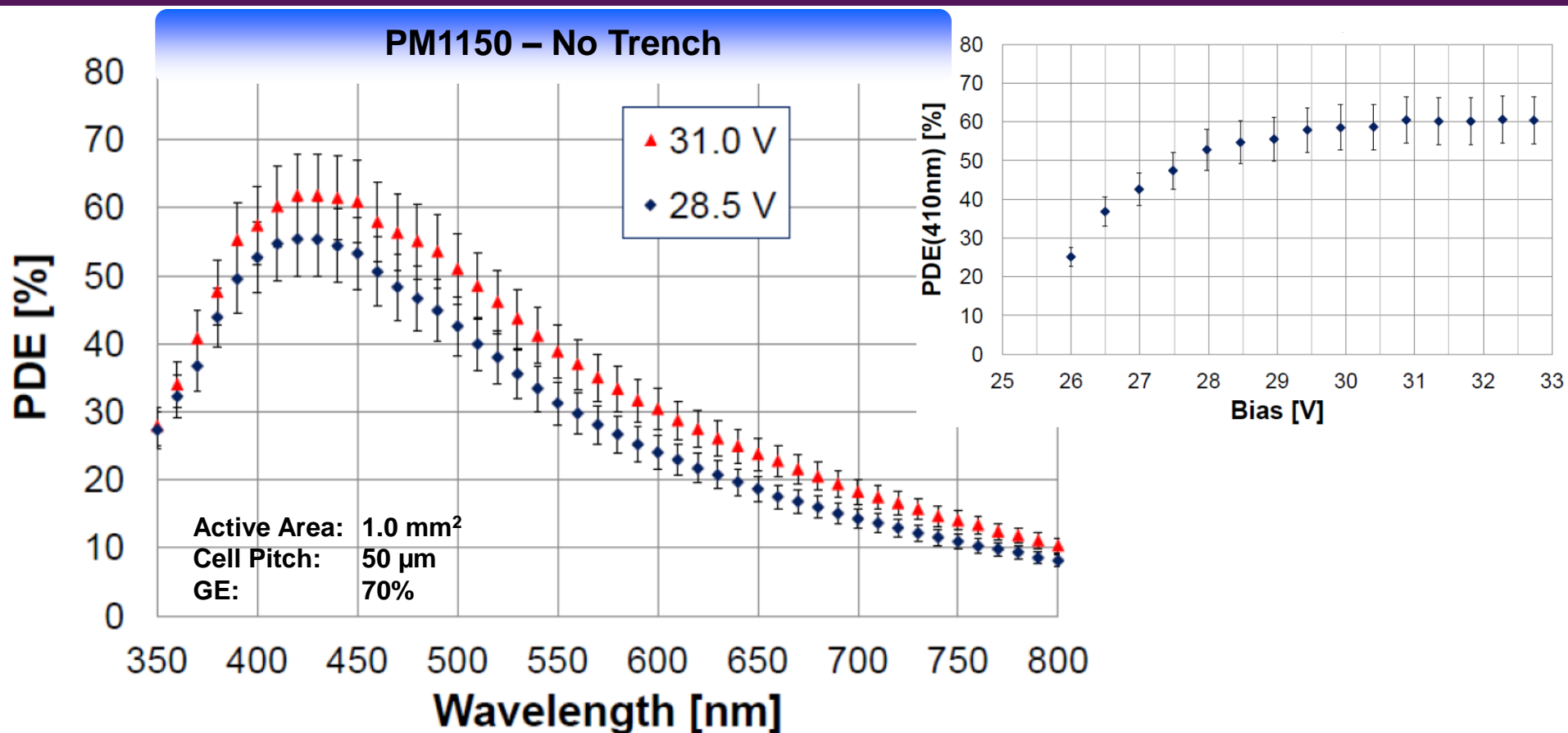
- Each microcell is completely surrounded by an optical trench isolation
- The trench is quite narrow with a width of  $1.0\ \mu\text{m}$
- Together with the trench technology an effective impurity gettering has been implemented



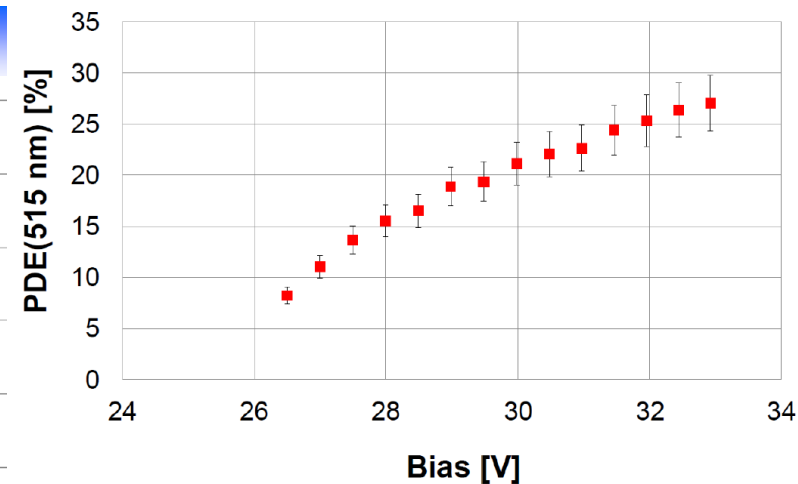
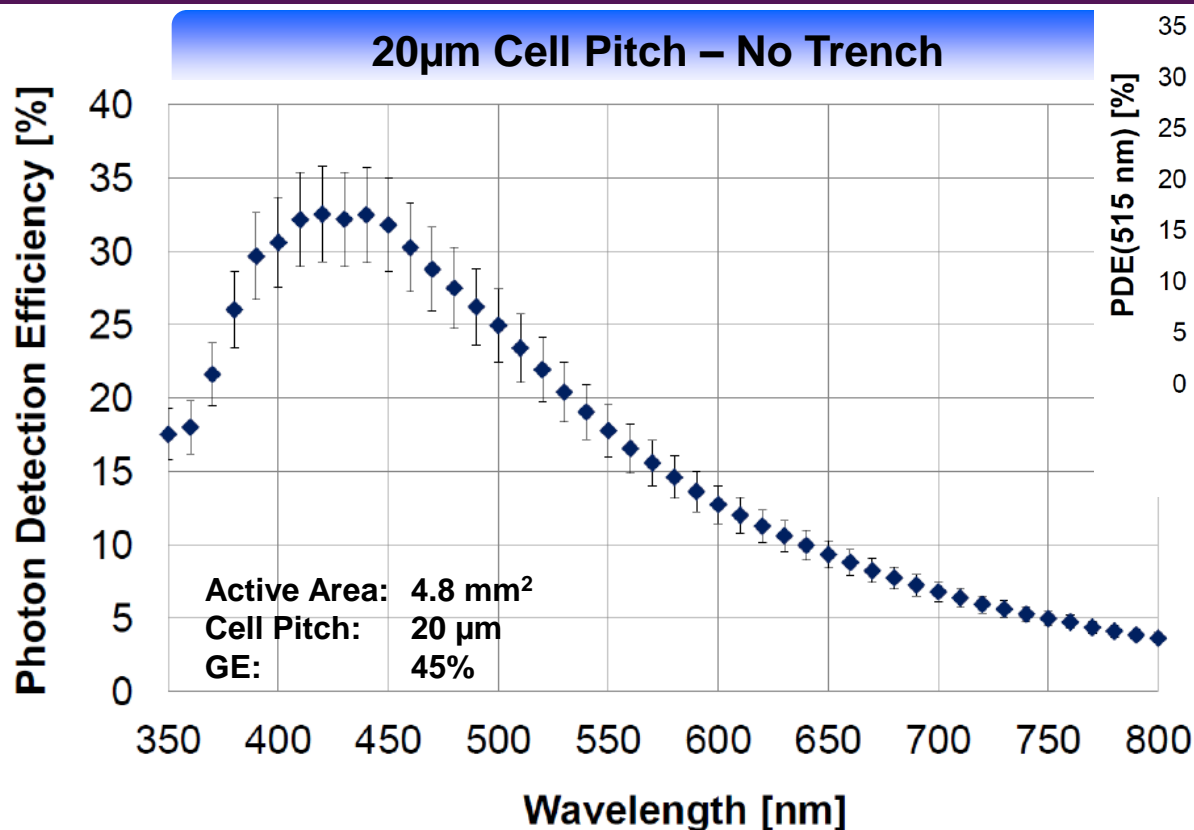


- Microcell sizes from 15μm up to 100μm realized
- Geometrical efficiency up to 70% for 50 μm microcell type



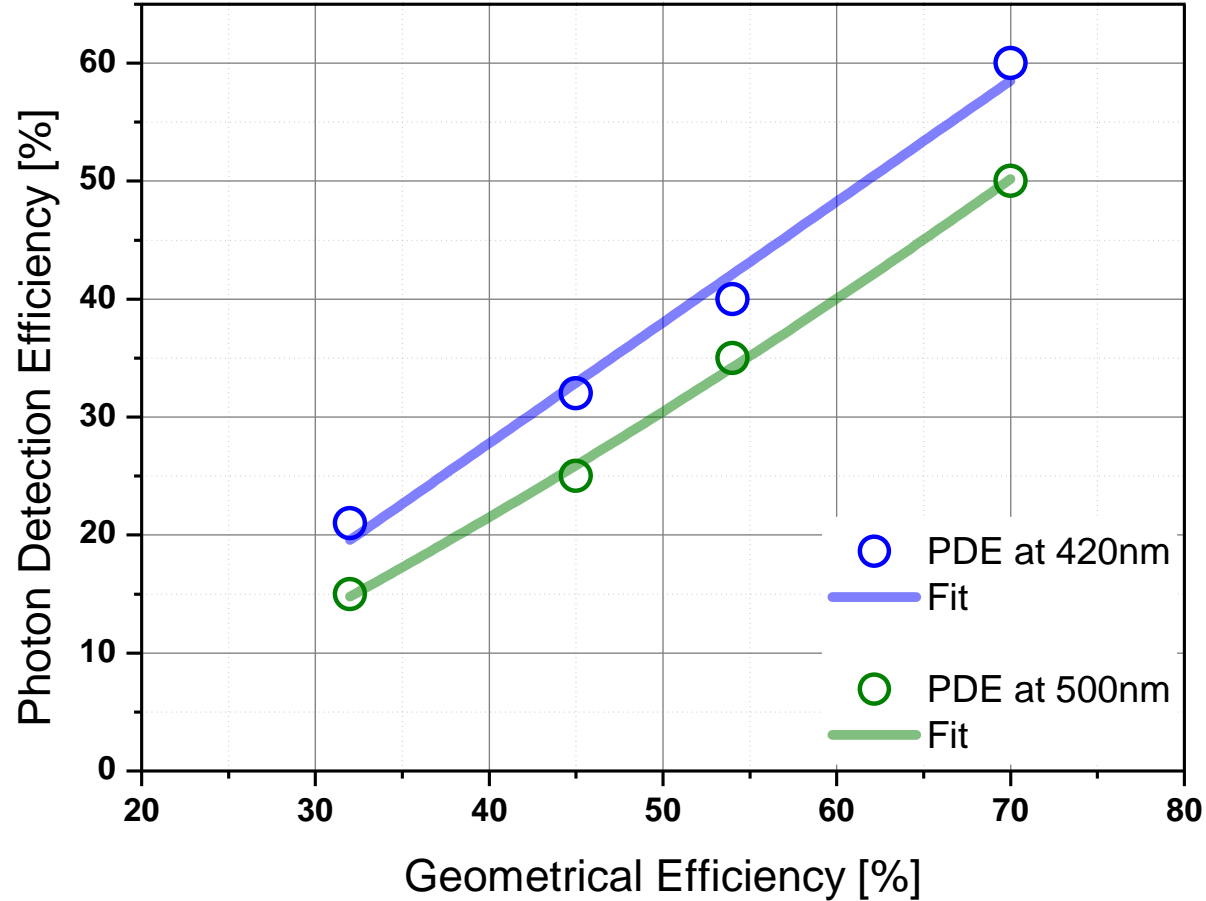


- Measurements performed by CERN / Iouri Musienko
- PDE is not affected by crosstalk and afterpulsing
- **60% PDE for blue light** (50% for green light)



- Measurements performed by CERN / Iouri Musienko
- PDE is not affected by crosstalk and afterpulsing
- **32% PDE for blue light (25% for green light)**

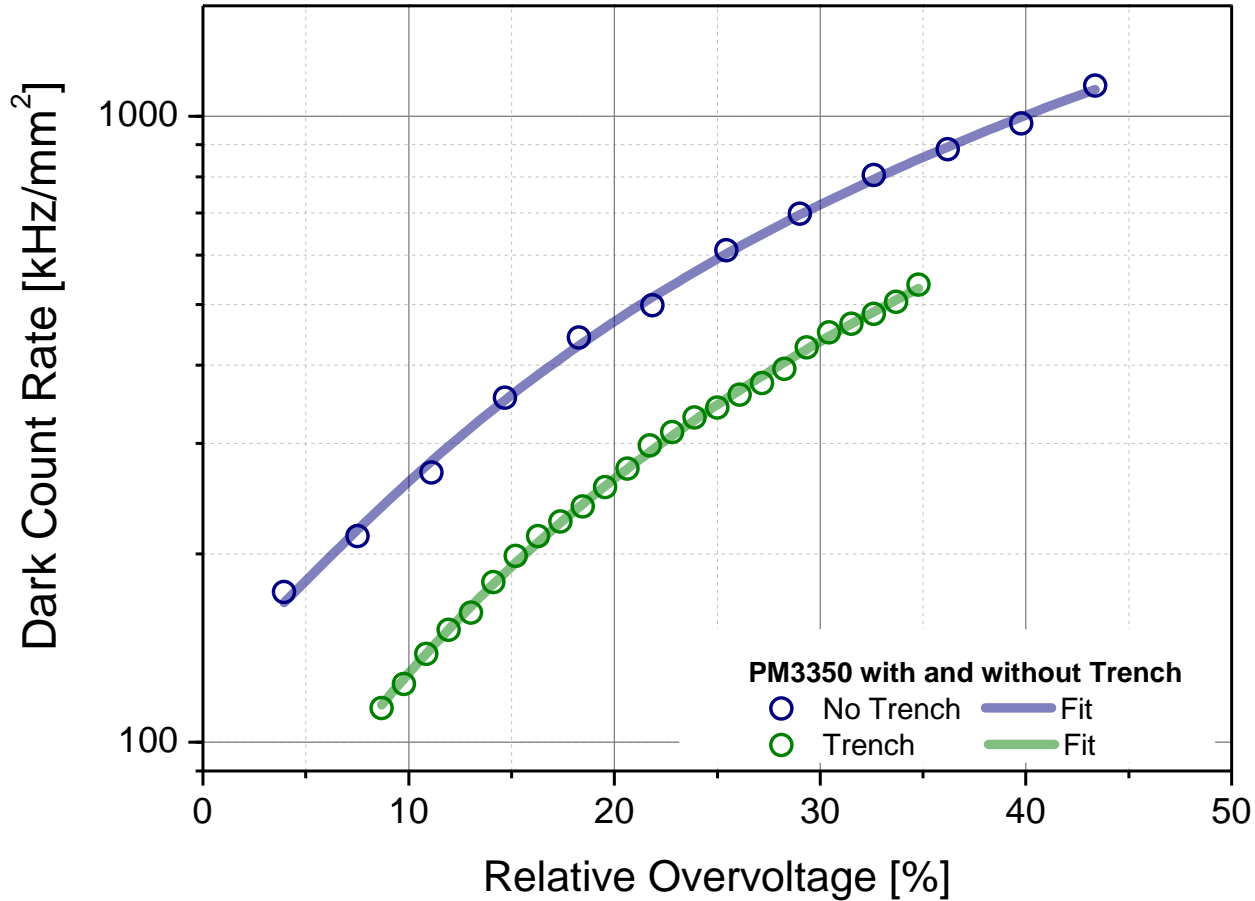
# Photo Detection Efficiency vs Geometrical Efficiency



- PDE in the blue range is not scaling exact linear with the geometrical efficiency
- A slightly lower efficiency of the active microcell edge compared to the center is indicated

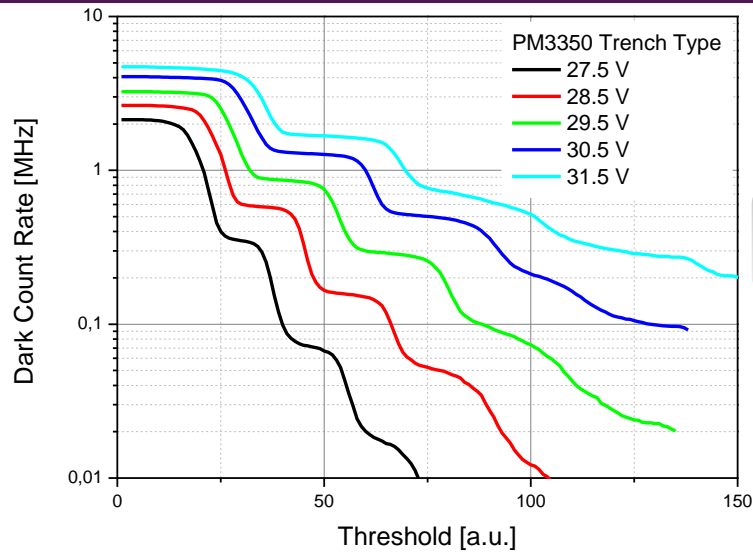






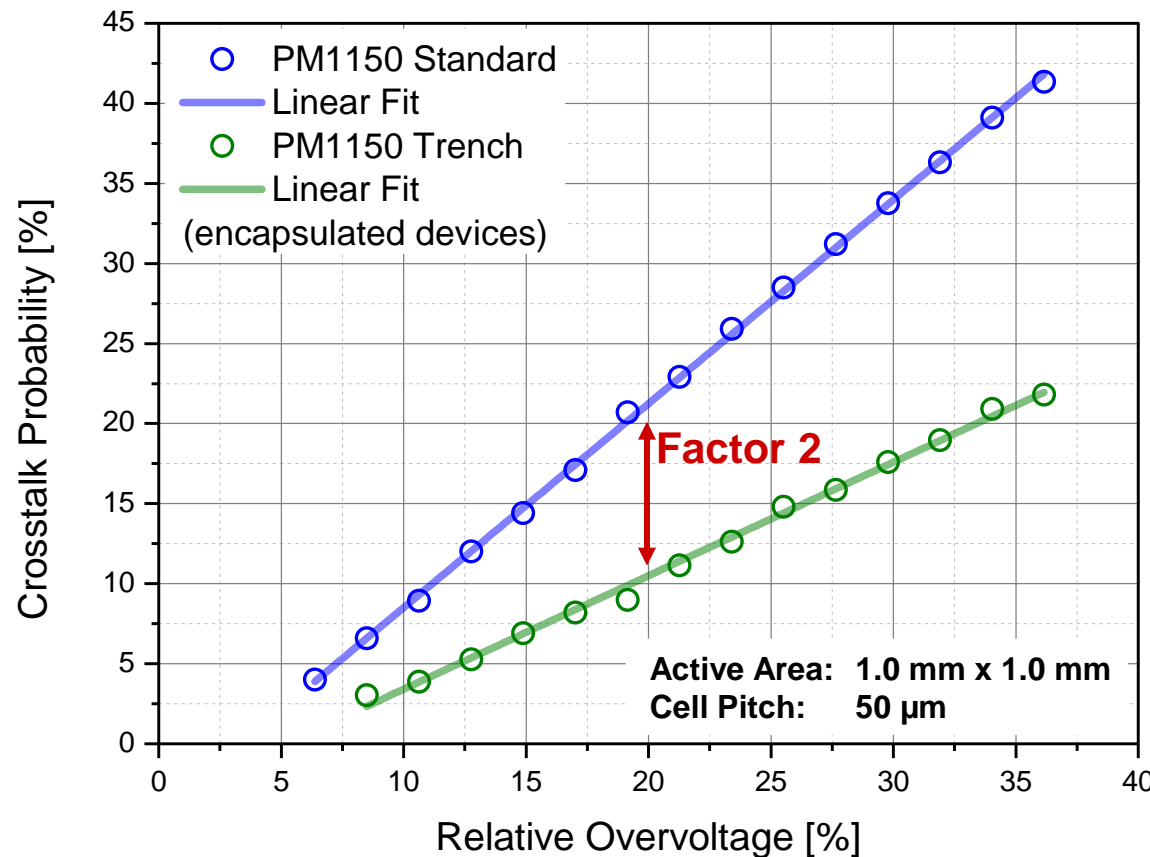
## Dark count rate at 20% overvoltage

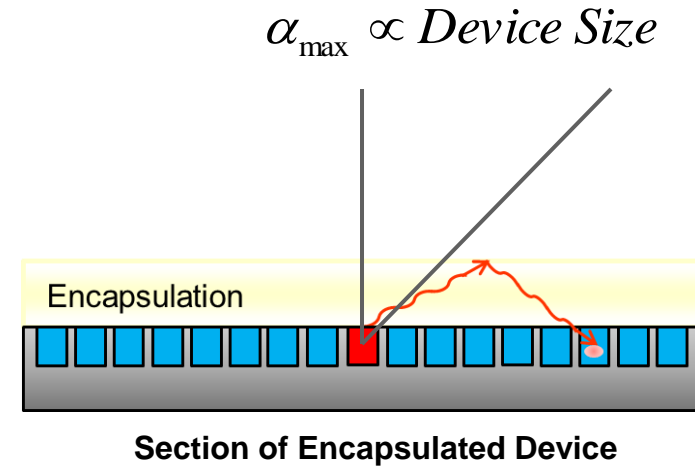
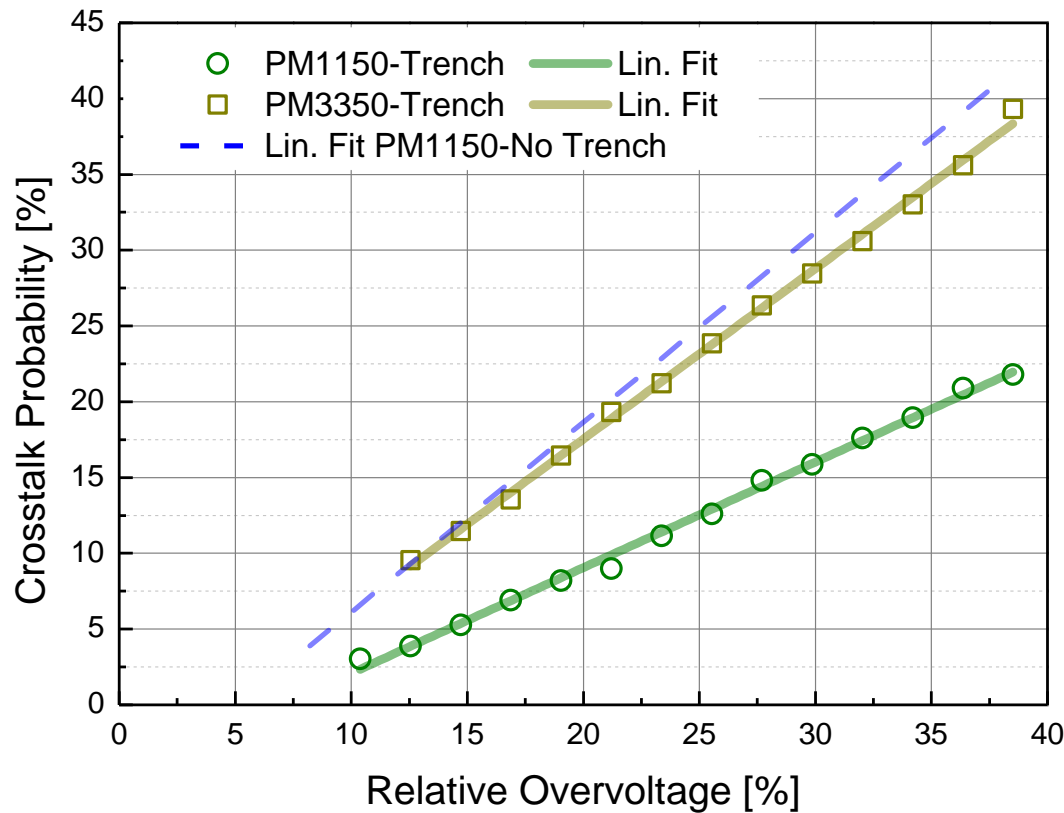
- standard technology  $\leq 500$  kHz/mm<sup>2</sup>
- trench technology  $\leq 300$  kHz/mm<sup>2</sup>



- Crosstalk evaluation based on dark rate versus threshold measurement
- PM1150 **no trench** and **trench** type encapsulated
- **10% crosstalk probability** at 20% overvoltage

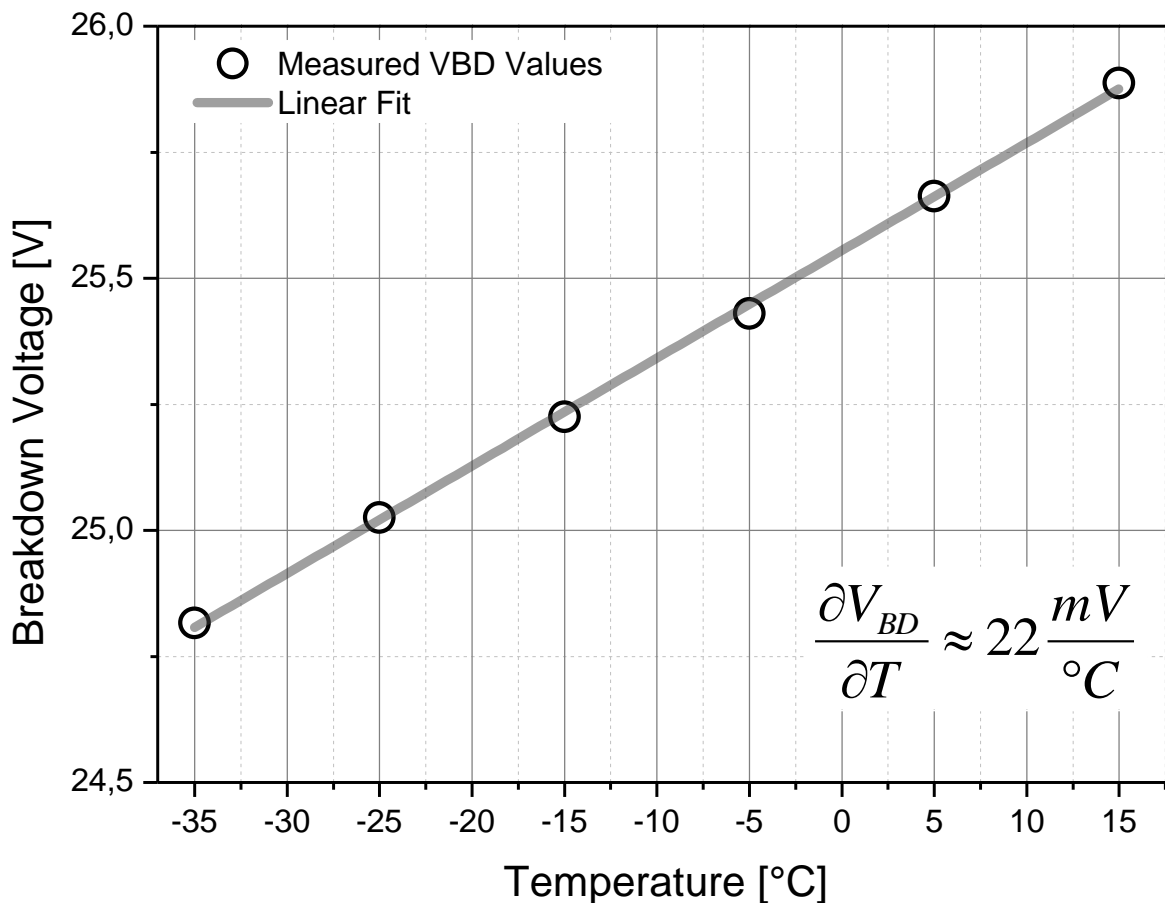
### PM1150: No-Trench and Trench Type





- The optical crosstalk probability increases with increasing active area
- Crosstalk probability of a **PM3350 with trench** is comparably to a **PM1150 without trench**
- Main contribution is caused by photons being reflected at the package interface

# Temperature Coefficient of the Breakdown Voltage ( $V_{BD}$ )



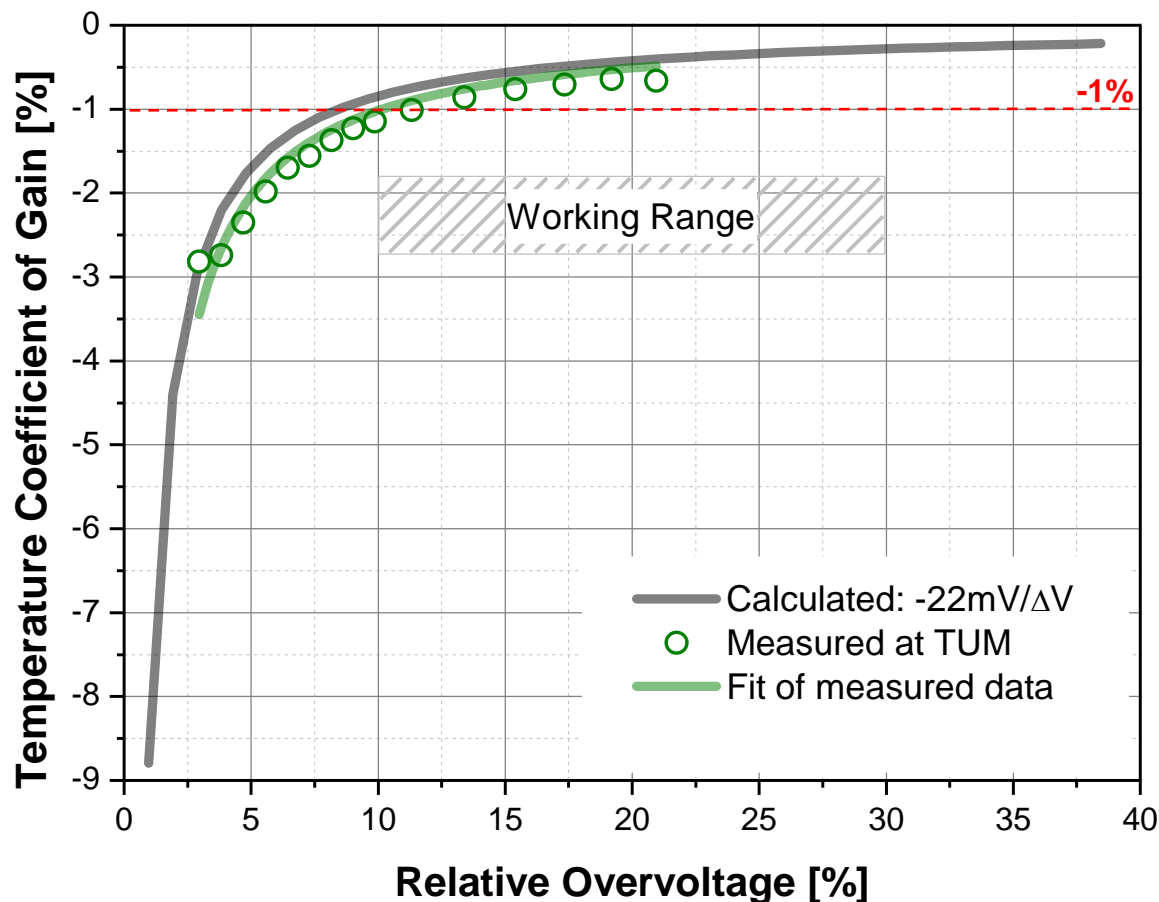
- Avalanche diodes have a positive temperature coefficient of the break down voltage
- For KETEK SiPMs this value is about **22 mV/°C**
- This temperature coefficient is affecting directly the temperature coefficient of the gain:

$$\frac{1}{G} \cdot \left( \frac{\partial G}{\partial T} \right) = - \frac{1}{\Delta V} \cdot \left( \frac{\partial V_{BD}}{\partial T} \right)$$
$$\approx \frac{-22mV}{\Delta V} \cdot K^{-1}$$

$G$  Gain  
 $\Delta V$  Overvoltage  
 $V_{BD}$  Breakdown Voltage  
 $T$  Temperature



# Temperature Coefficient of the Gain



- With increasing overvoltage the temperature coefficient of the gain is decreasing drastically
- In the recommended working range of 10% to 30% OV the temperature coefficient of the gain is below 1%.

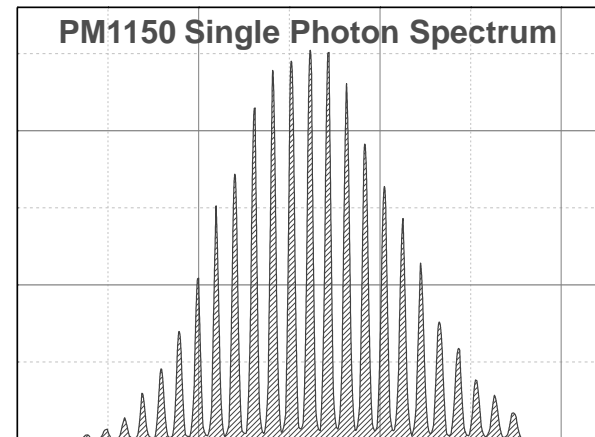
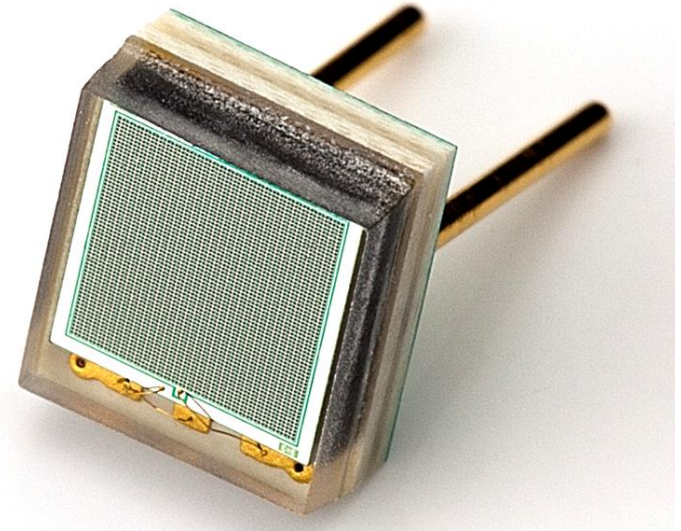
$$\text{Huge Overvoltage} + \text{Very Small } \frac{\partial V_{BD}}{\partial T} = \text{Minimal } \left| \frac{1}{G} \cdot \left( \frac{\partial G}{\partial T} \right) \right|$$

## KETEK Silicon Photomultipliers - Fast Single Photon Counting -

- High PDE up to **60 %** for 50 $\mu$ m cell type
- Optimized for **blue light sensitivity**
- Low dark count rate and low cross talk
- Huge bias voltage range of stable operation
- Extremely **low temperature coefficient**

## PM3350

3 x 3mm<sup>2</sup> active area; 50  $\mu$ m microcell type;  
peak wavelength 420 nm; plastic package



# Additional Slides



KETEK

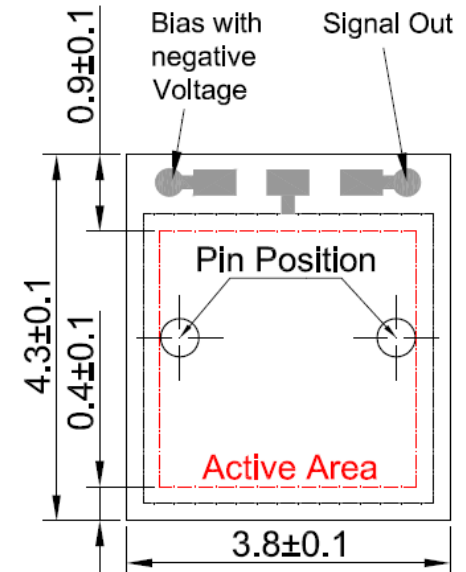
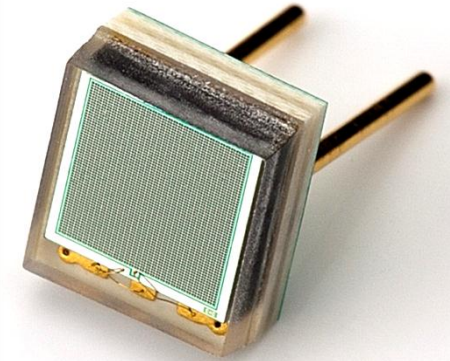
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# Scheduled Portfolio - Completely Available until End 2012

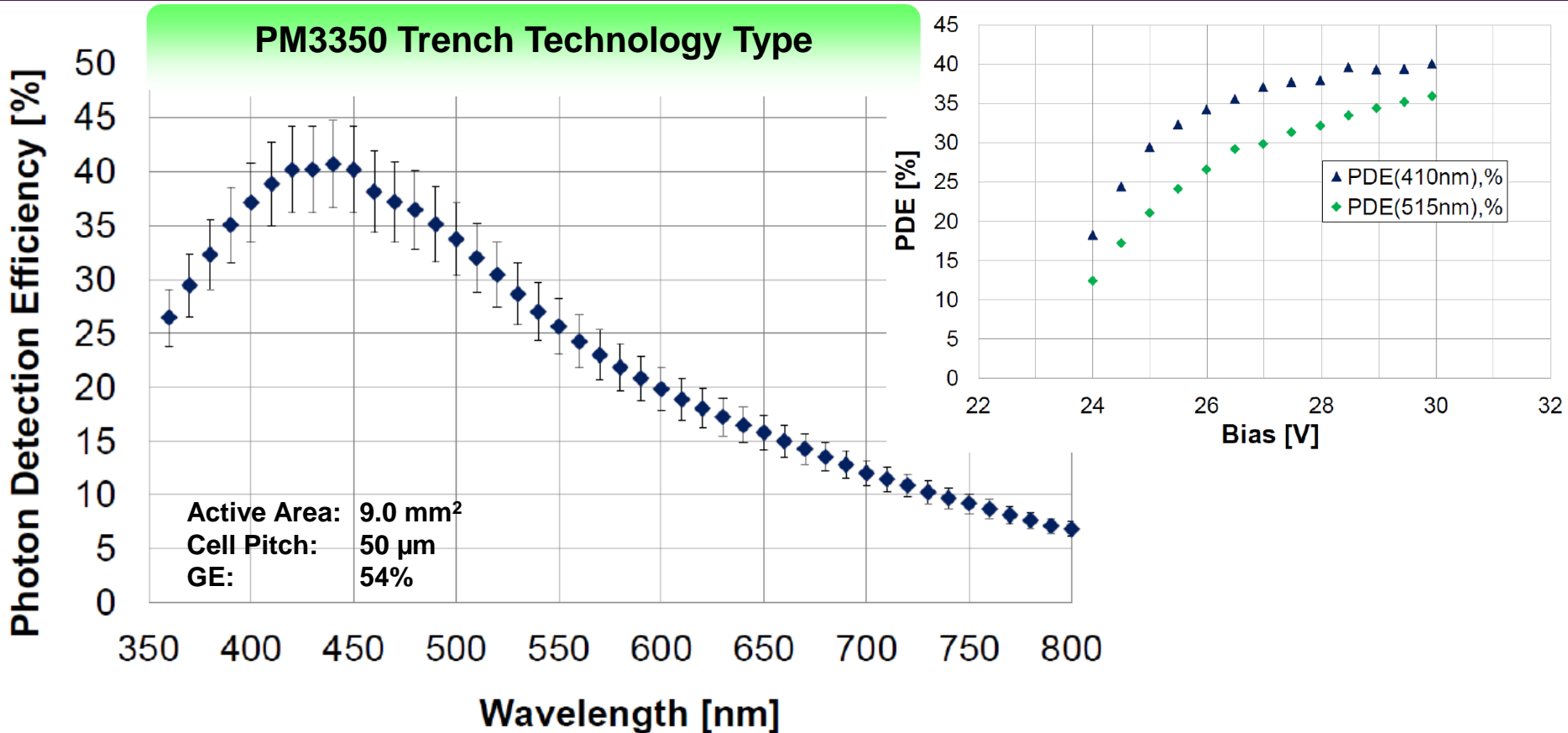
	Active Area [mm]	Cell Pitch [ $\mu\text{m}$ ]	Standard	Trench
PM11 SMD	1.2 x 1.2	50 $\mu\text{m}$	X	X
	1.2 x 1.2	75 $\mu\text{m}$	---	X
	1.2 x 1.2	100 $\mu\text{m}$	---	X
PM22 SMD	2.0 x 2.0	50 $\mu\text{m}$	X	X
	2.0 x 2.0	100 $\mu\text{m}$	---	X
PM33 Pin SMD	3.0 x 3.0	50 $\mu\text{m}$	X	X
	3.0 x 3.0	60 $\mu\text{m}$	X	X
	3.0 x 3.0	75 $\mu\text{m}$	X	X
PM66 - Pin	6.0 x 6.0	60 $\mu\text{m}$	---	X

## PM3350 - Pin

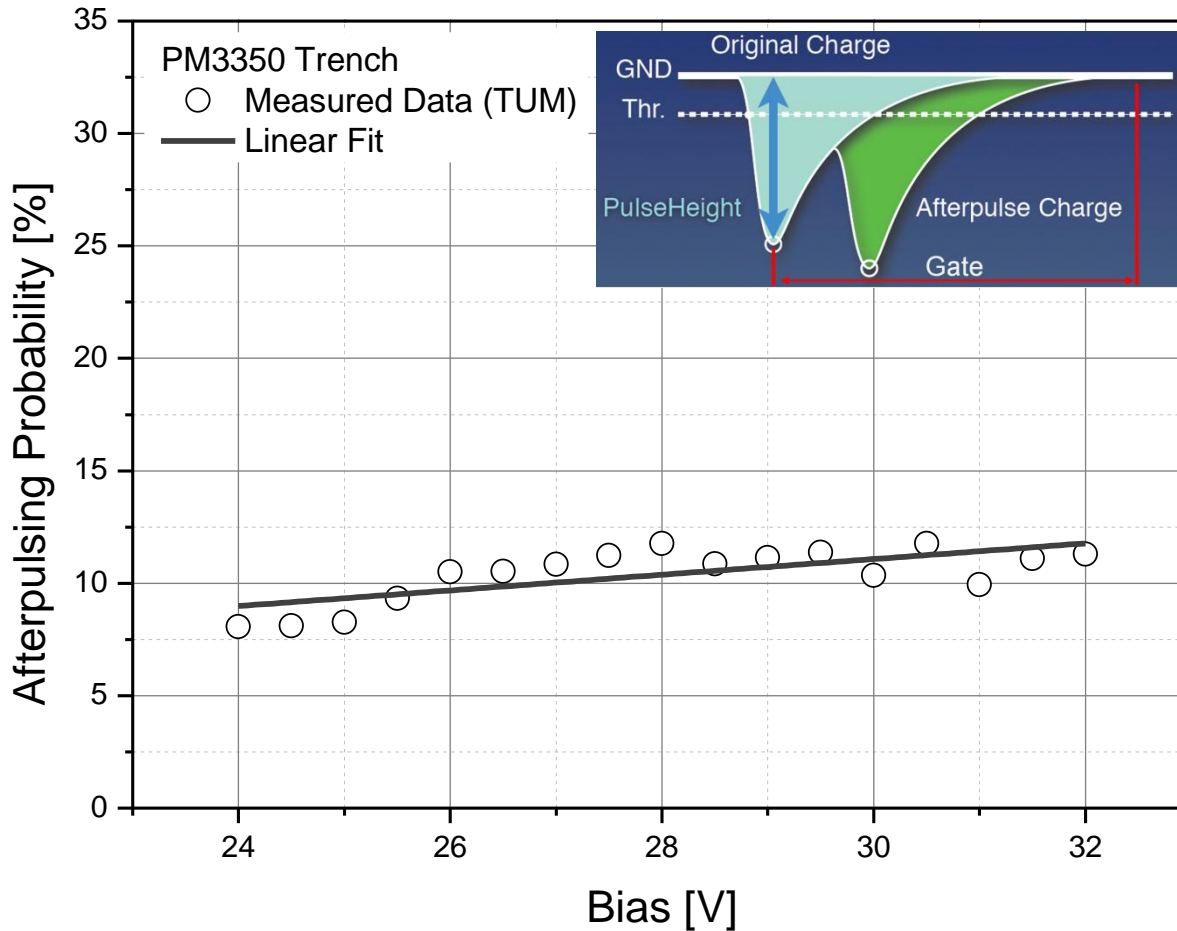
3 x 3mm<sup>2</sup> active area; 50  $\mu\text{m}$  cell type; peak wavelength 420 nm; plastic package



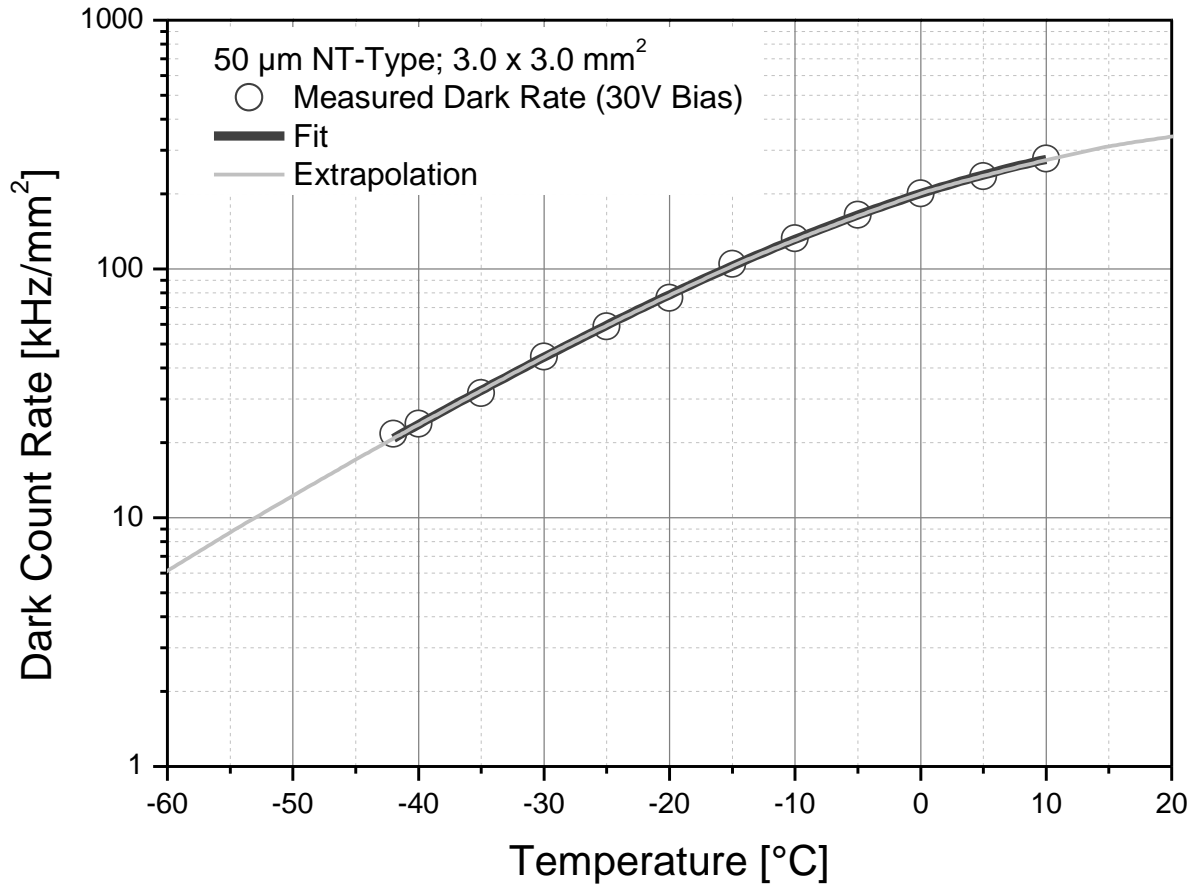




- Measurements performed by CERN / Iouri Musienko
- PDE is not affected by crosstalk and afterpulsing
- **40% PDE for blue light (35% for green light)**



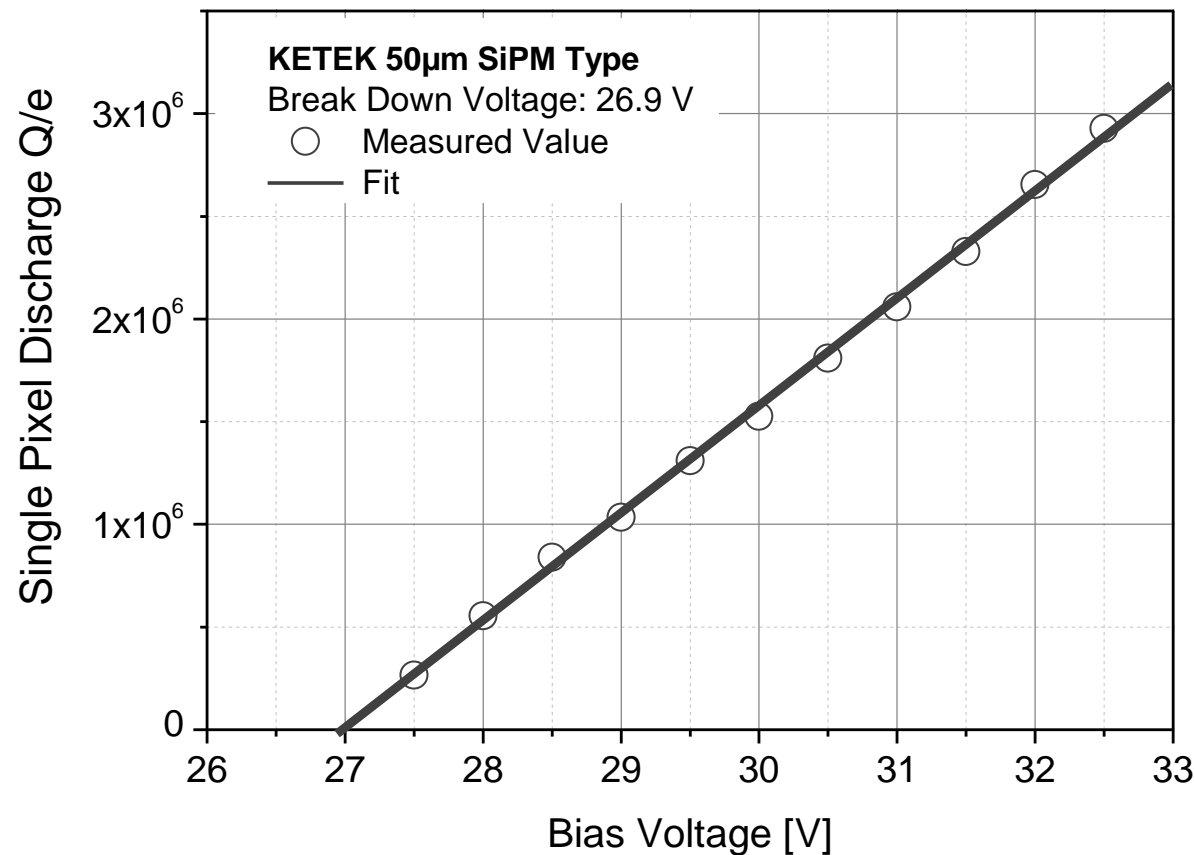
- After pulses are generated by trapped and time delayed re-emitted electrons.
- Measurement is based on pulse counting of events within the recovery time of single pulses
- The real afterpulse probability is smaller
- The after pulse probability for KETEK devices is below 10%



- The dark rate is scaling with the carrier density in silicon

$$n(T) \sim T^{1.5} \cdot e^{-\frac{E_g}{2 \cdot k \cdot T}}$$

- Additional effects like trapping and surface current cause deviations from this formula
- Rule of thumb: Every 10°C the dark rate is reduced by factor 2



- The single pixel discharge defines the gain of a SiPM
- The real gain is slightly lower due to the excess noise (dark count rate, afterpulses, cross talk)
- For a KETEK SiPM the gain is approximately **2 Million** for a 50 $\mu$ m cell pitch device

$$Gain = \frac{C_{Pixel} \cdot \Delta V}{e} \propto GE \cdot \Delta V$$

$C_{Pixel}$  Capacitance of Microcell  
 $\Delta V$  Overvoltage  
 $GE$  Geometrical Efficiency  
 $e$  Elementary Charge